

UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
United States Patent and Trademark Office
Address: COMMISSIONER OF PATENTS AND TRADEMARKS
P.O. Box 1459
Alexandria, Viginia 22313-1450
www.uspto.gov

FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO	
06/08/1999	HIROTO HORIKAWA	101809.03	5673	
25944 7590 05/16/2003 OLIFF & BERRIDGE, PLC		EXAM	EXAMINER	
28		KIM, PETER B		
9		ART UNIT	PAPER NUMBER	
		2851		
		DATE MAILED: 05/16/2003	1	
	o5/16/2003 RRIDGE, PLC	06/08/1999 HIROTO HORIKAWA 590 05/16/2003 RRIDGE, PLC 28	FILING DATE 06/08/1999 HIROTO HORIKAWA 101809.03 RRIDGE, PLC 28 A, VA 22320 ART UNIT 2851	

Please find below and/or attached an Office communication concerning this application or proceeding.

		<i></i>		No No matter	1, /
		Application No).	Applicant(s)	W
		09/327,621		HORIKAWA, HIROTO	
÷	Office Action Summary	Examiner		Art Unit	
		Peter B. Kim		2851	dress
-	- The MAILING DATE of this communication app	pears on the cov	er sheet with	tne correspondence ad	ui 633
Daniel and San	- D nlv				
THE N - Exter after - If the - If NO - Failur	DRTENED STATUTORY PERIOD FOR REPLICATION. MAILING DATE OF THIS COMMUNICATION. Insigns of time may be available under the provisions of 37 CFR 1.7 SIX (6) MONTHS from the mailing date of this communication. Period for reply specified above is less than thirty (30) days, a reply period for reply is specified above, the maximum statutory period re to reply within the set or extended period for reply will, by statutely received by the Office later than three months after the mailing and patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event, he by within the statutory will apply and will exp	minimum of thirty (ire SIX (6) MONTI	ly be timely filed 30) days will be considered time 35 from the mailing date of this of the control of the co	ly. communication.
1)	Responsive to communication(s) filed on	·			
	() - :- FINIAL 2h) ☐ T	his action is not	n-final.		
2a)⊠ 3)□		vance except fo	r formal matt	ers, prosecution as to t	he merits is
Disposit	closed in accordance with the practice under ion of Claims	I Ex parto qua	,	. 11, 453 O.G. 210.	
4)⊠	Claim(s) 26-94 and 97-104 is/are pending in	the application			
	4a) Of the above claim(s) is/are withdr	awn from consi	deration.		
5)🖂	07 104 is/are allow	ved.			
6)⊠					
7)🖂	Claim(s) 43 and 44 is/are objected to.				
8)	Claim(s) are subject to restriction and	l/or election req	uirement.		
Applica	tion Papers				
9)	The specification is objected to by the Exami	ner.	-instad to by t	he Examiner.	
10)	The drawing(s) filed on is/are: a) □ ac	cepted or b) 0	hold in abev	ance See 37 CFR 1.85(a	a).
	Applicant may not request that any objection to The proposed drawing correction filed on	the drawing(s) b		lisapproved by the Exam	niner.
11)	The proposed drawing correction filed on	is. a) apr	e action.		
	If approved, corrected drawings are required in	Evaminer	,o dollor		
1	The oath or declaration is objected to by the	EXAMINION.			
Priority	under 35 U.S.C. §§ 119 and 120	nian priority und	er 35 U.S.C.	§ 119(a)-(d) or (f).	
13)∑	Acknowledgment is made of a claim for fore	eigh phonty and	C, 00 0.0.0.	J (-) ()	
\ ;	a)⊠ All b)□ Some * c)□ None of:		received		
	1. Certified copies of the priority docum	ents have been	received in	Application No. 08/935	<u>445</u> .
	2. ☐ Certified copies of the priority docum	ents nave been	nte have hee	received in this Natio	nal Stage
	3. Copies of the certified copies of the paper application from the International * See the attached detailed Office action for a	list of the certifi	ed copies no	t received.	
14)	* See the attached detailed Office action for d Acknowledgment is made of a claim for dom	nestic priority un	der 35 U.S.C	:. § 119(e) (to a provision	onal application).
1	a) The translation of the foreign language Acknowledgment is made of a claim for don	nrovisional abl	olication nas	Deell leccived.	
20 🗆 🖪	nent(s) Notice of References Cited (PTO-892) Notice of Draftsperson's Patent Drawing Review (PTO-948 nformation Disclosure Statement(s) (PTO-1449) Paper No	3) o(s) <u>30</u> .	4) Intervie 5) Notice 6 6) Other:	w Summary (PTO-413) Pape of Informal Patent Application	er No(s) n (PTO-152)

· Application/Control Number: 09/327,621

Art Unit: 2851

DETAILED ACTION

Applicant's arguments filed on Mar. 21, 2003 (paper #31) have been fully considered.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 38-42, and 45-53 are rejected under 35 U.S.C. 103(a) as being unpatentable over Nishi in view of Negishi.

Nishi discloses in Figures 1 and 2 and col. 8, line 14 through col. 10, line 4, a projection exposure apparatus with a base (19) which holds the scanning stage (first stage)(20) and the fine adjustment stage (second stage)(21) which holds the mask (7) and movable mirror (33, 34A, 34B) for laser interferometers (35, 36A, 36B) which detect a displacement of the fine adjustment stage. Nishi discloses the laser interferometer 35 located on base (19) that supports the first and the second stage (col. 9, lines 33-35). Nishi also discloses the illumination system (22), projection optical system (13), substrate (14) and substrate stage with movable mirror and laser interferometer. Nishi also discloses driving the fine adjustment stage to prevent a positional error when the scanning stage is accelerated or decelerated (col. 13, line 28-60). Although Nishi does not disclose the substrate located on the fine adjustment stage and the scanning stage, it would have been obvious to one of ordinary skill in the art at the time of the invention to provide the substrate stage with such an arrangement because Nishi teaches such arrangement with the mask stage. Nishi discloses a means for moving the scanning stage with electromagnetic

Page 3

Art Unit: 2851

actuators (Fig. 3), but Nishi does not disclose electromagnetic actuators for moving the fine adjustment stage. Nishi also does not disclose a cooling unit that cools the actuators with the cooling fluid from the actuators arranged in the direction perpendicular to the scanning direction with respect to the scanning stage. Negishi discloses in figures 1-4 and col. 3, line 20 - col. 7, line 35, electromagnetic actuators for moving het scanning stages of an exposure apparatus in xand y-directions. Negishi discloses the stationary member having a coil of the electromagnetic actuator located on the stationary base relative to the moving stage and the movable magnetic portion located on the moving stage. Negeshi discloses a pair of subactuators that are parallelly arranged (fig. 1, ref. 70a, 70b). Negishi also discloses cooling unit that cools the stationary member of the electromagnetic actuator in direction perpendicular and parallel to the scanning direction (Fig. 4). Therefore, it would have been obvious to one of ordinary skill in the art at the time of invention to provide as the fine adjustment stages, the stage with electromagnetic actuators and the cooling unit in view of Negishi to the invention of Nishi in order to more efficiently produce semiconductor elements or liquid crystal display element which is well known product of scanning exposure apparatus. Also, since Negishi teaches cooling of the stationary member of the actuator in order to prevent flexure of the movable member due to the heat in col. 1, lines 43-66, it would be obvious to provide cooling to actuators of the scanning stage as well as the fine adjustment stage.

Allowable Subject Matter

Claims 26-37, 54-94, and 97-104 are allowed.

Application/Control Number: 09/327,621

Art Unit: 2851

Claims 43 and 44 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

None of the prior art of record teaches the cooling unit circulating the cooling fluid from a portion near an optical path of the light beam from the interferometer toward the first coil member or the second coil member in combination with the stage apparatus comprising a first and a second stage.

None of the prior art of record teaches a stage apparatus comprising a first stage and a second stage, a first actuator driving the second stage and a second actuator to drive the second stage with a thrust larger than the thrust by the first actuator.

Response to Arguments

Applicant argues that the prior art does not disclose the interferometer located on the base. However, Nishi discloses the laser interferometer 35 located on base (19) that supports the first and the second stage (col. 9, lines 33-35).

Applicant also argues that motivation or suggestion for combining the reference is lacking. However, Negishi teaches in col. 1, lines 43-66 the need for cooling the electromagnetic actuators, and since Nishi uses electromagnetic actuators, Nishi would also need to cool the actuators.

Conclusion

THIS ACTION IS MADE FINAL. Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

Application/Control Number: 09/327,621

Art Unit: 2851

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the mailing date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Peter Kim whose telephone number is (703) 305-0105. The examiner can normally be reached on Monday-Thursday from 6:30 AM to 4:00 PM. The examiner can also be reached on alternate Fridays during the same hours.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Russ Adams, can be reached on (703) 308-2847. Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 308-0956.

Peter B. Kim

Patent Examiner

May 13, 2003

RUSSELL ADAMS

SUPERVISORY PATENT EXAMINER

TECHNOLOGY CENTER 2800